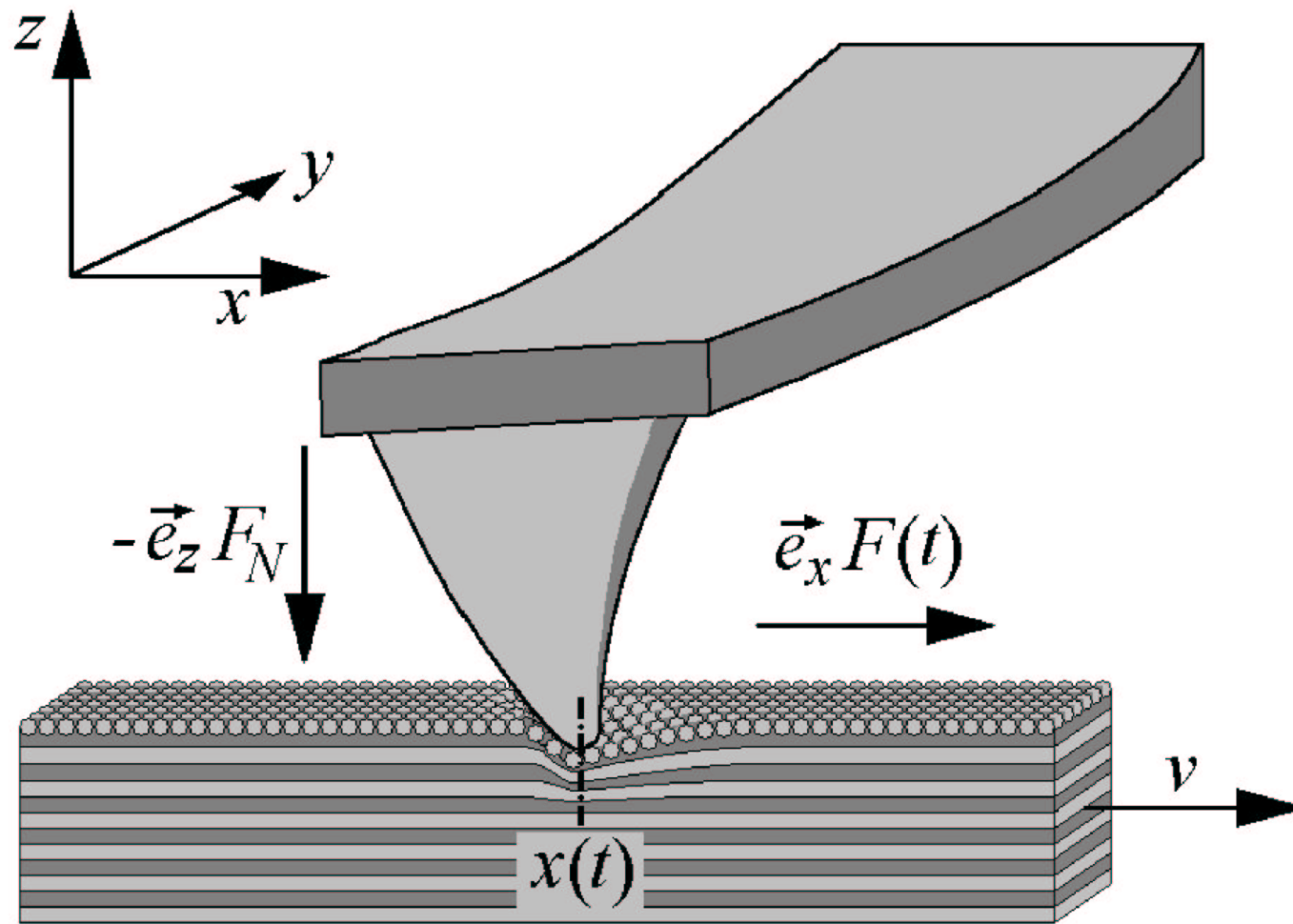
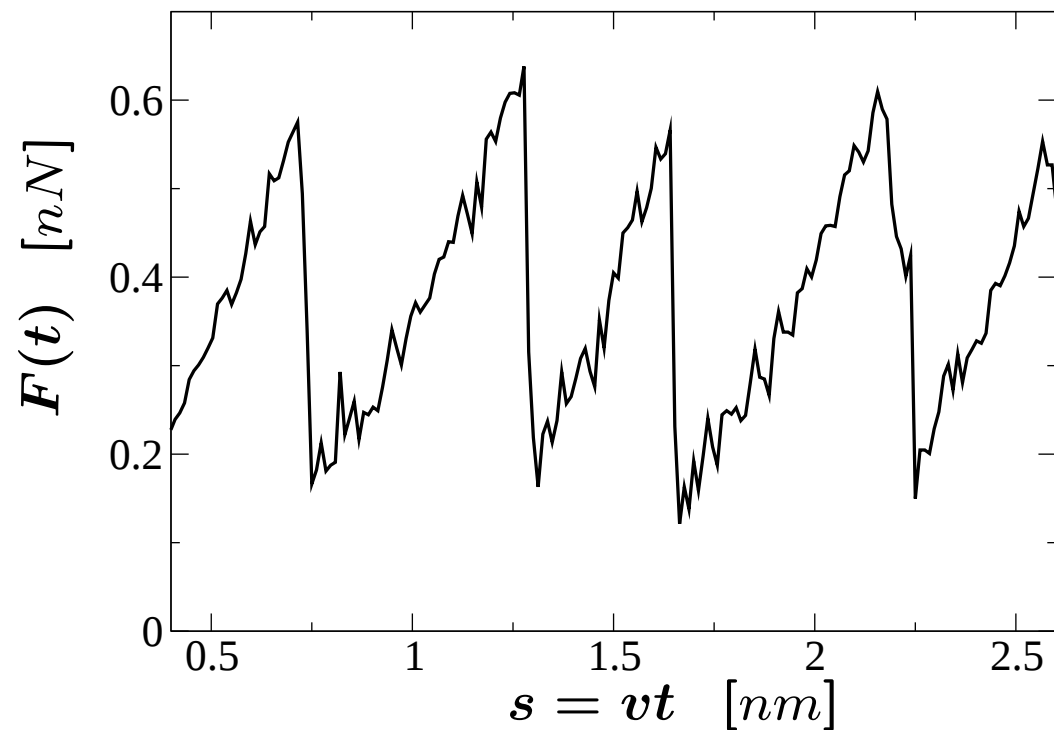
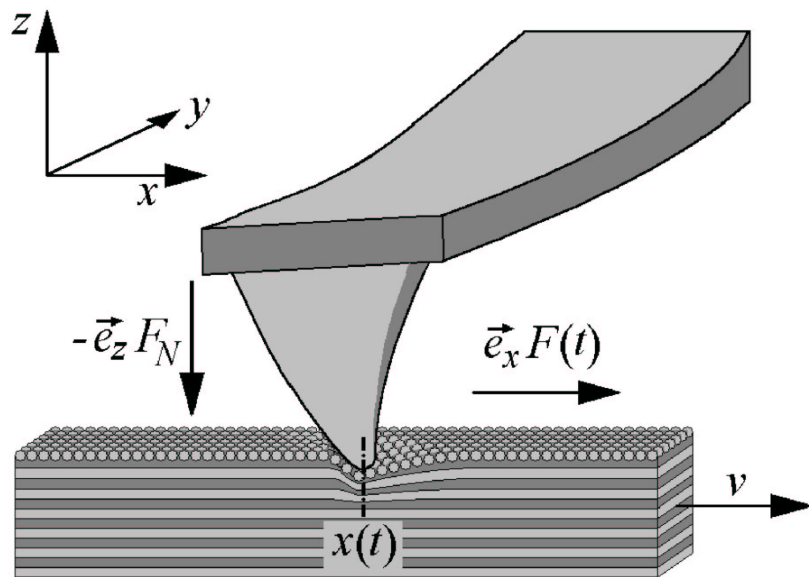




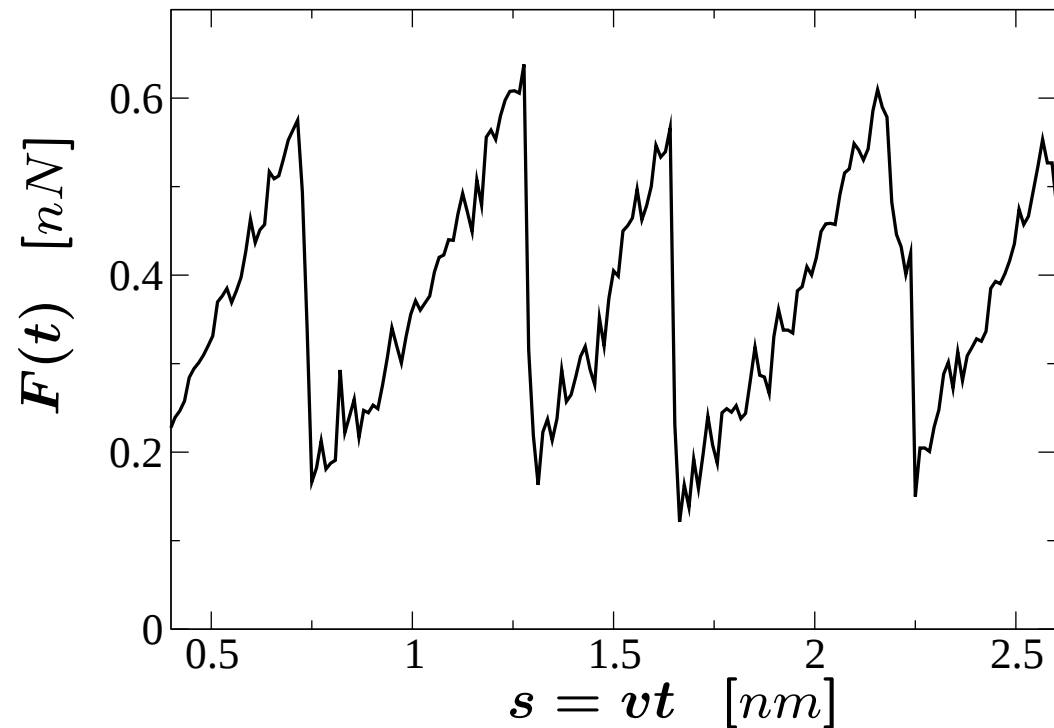
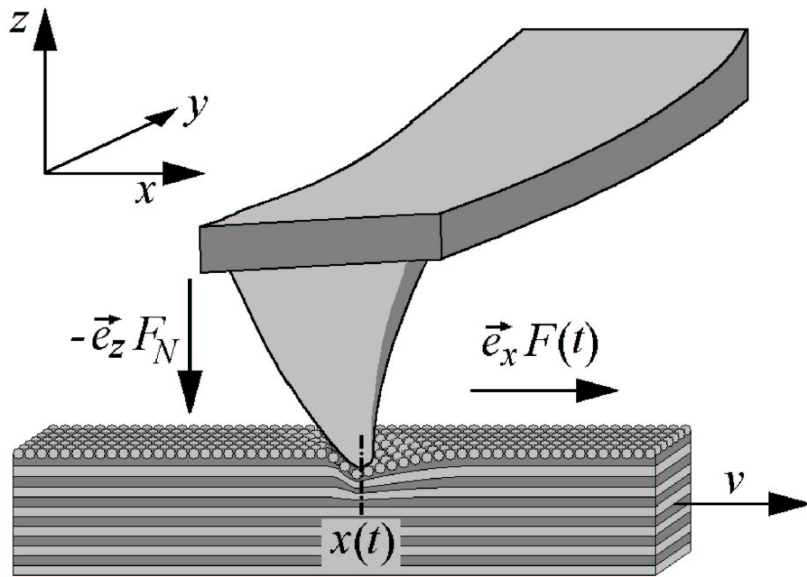
- cantilever dimensions $\approx 200 \mu\text{m} \times 50 \mu\text{m} \times 1 \mu\text{m}$
- tip height and basis radius $\approx 5 \mu\text{m} \times 1 \mu\text{m}$
- tip apex radius $\approx 10 \text{ nm}$
- lattice constant $L \approx 0.5 \text{ nm}$

Friction Force Microscopy



- stick-slip motion
- “atomic resolution” ($L \approx 0.5 \text{ nm}$)
- thermal noise effects

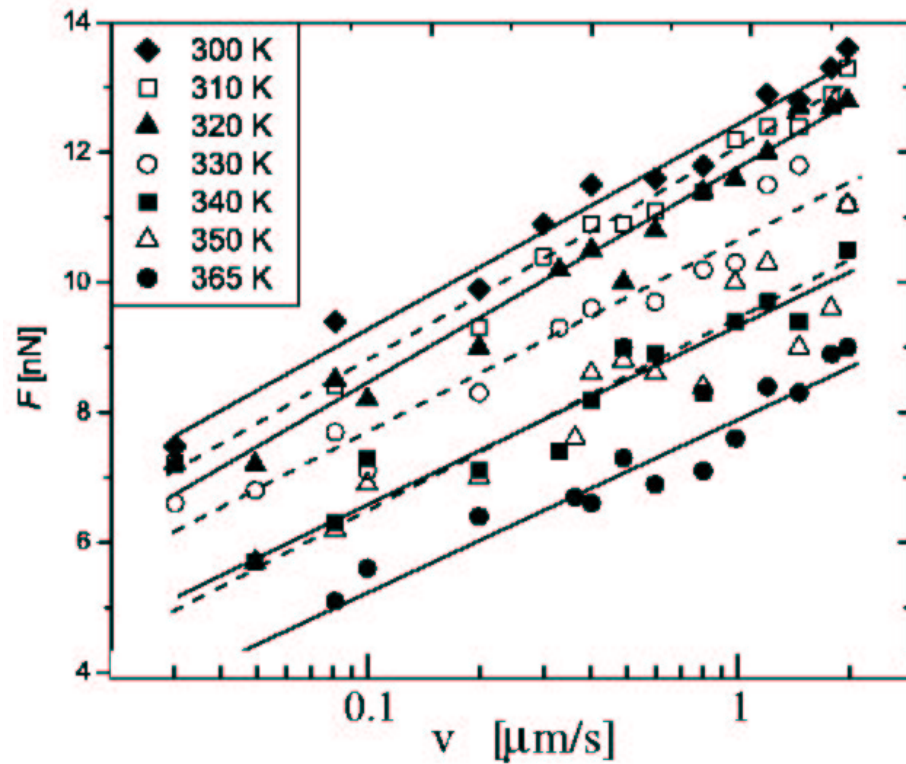
Friction Force Microscopy



- stick-slip motion
- “atomic resolution” ($L \approx 0.5$ nm)
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Quantity of main interest: $\bar{F} := \lim_{t \rightarrow \infty} \frac{1}{t} \int_0^t dt' F(t')$

$\bar{F}$ versus v



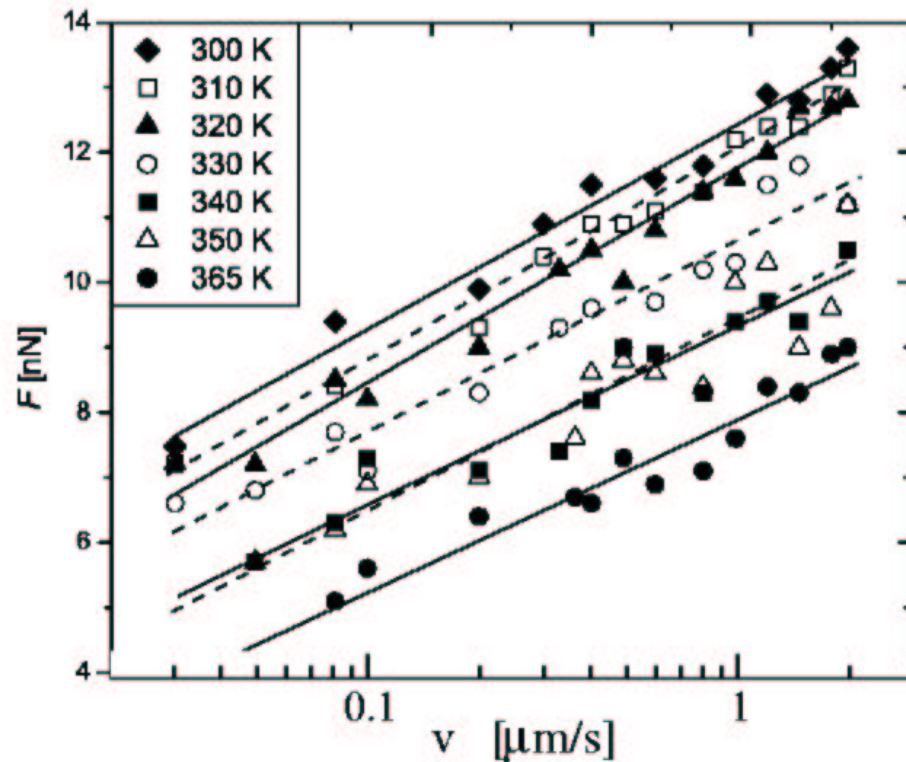
Sills and Overney, PRL 91, 095501 (2003)

glassy polystyrene surface

$F_N = 15$ nN

- thermal noise matters

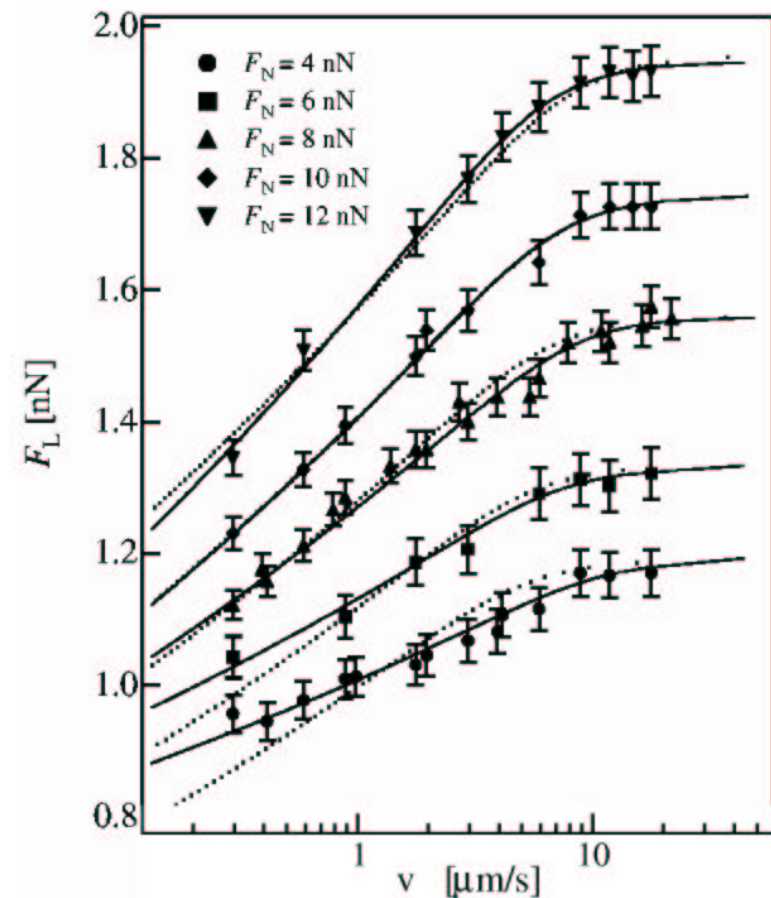
$\bar{F}$ versus v



Sills and Overney, PRL 91, 095501 (2003)
glassy polystyrene surface

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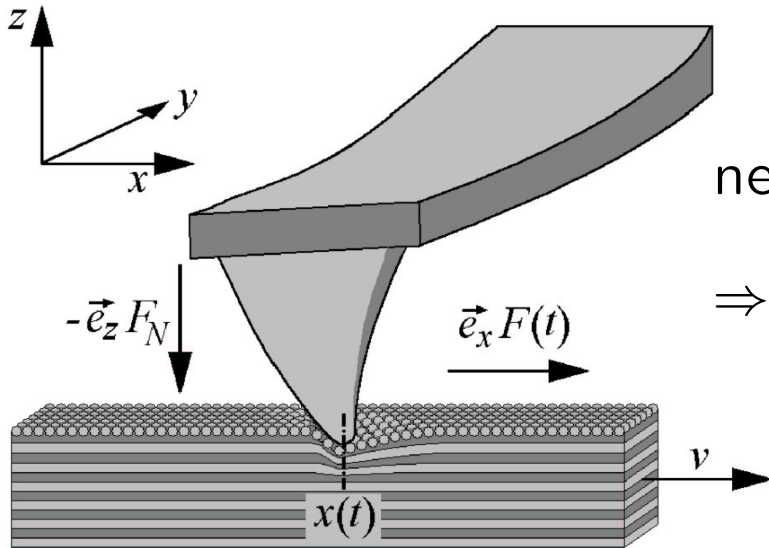


Riedo et al., PRL 91, 084502 (2003)
mica surface

$T = 293$ K

- “plateaux” at large v

Model

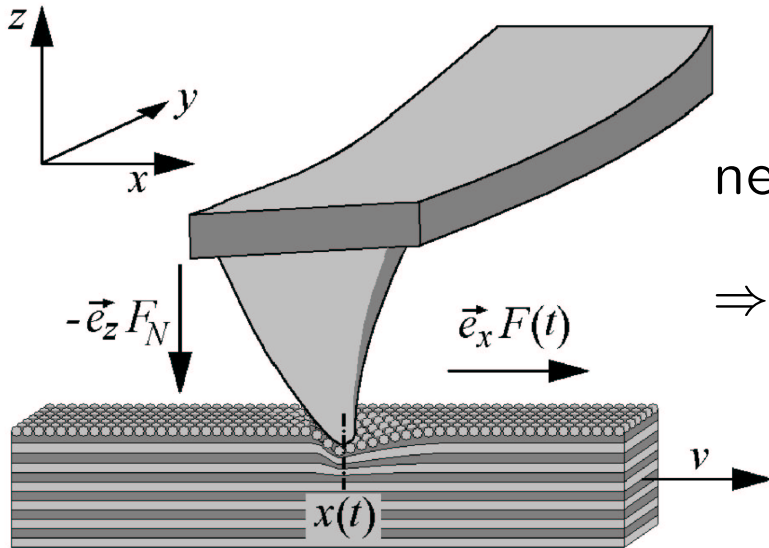


neglect “fast” thermal fluctuations of molecules
 $\Rightarrow$ 2 “slow” state variables/collective coordinates:

x -coordinate of tip apex (rest position $x = 0$)

s : position of substrate along x -axis

Model



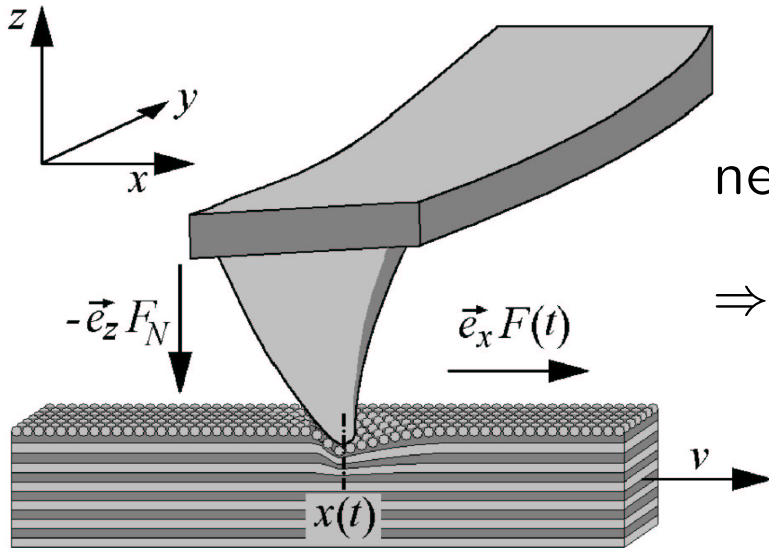
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- given x and s , the entire “global” configuration is uniquely fixed
- x, s “slow” $\Leftrightarrow$ “fast” molecular fluctuations always close to equilibrium
- $s = vt$ externally imposed (still “slow”)

Model



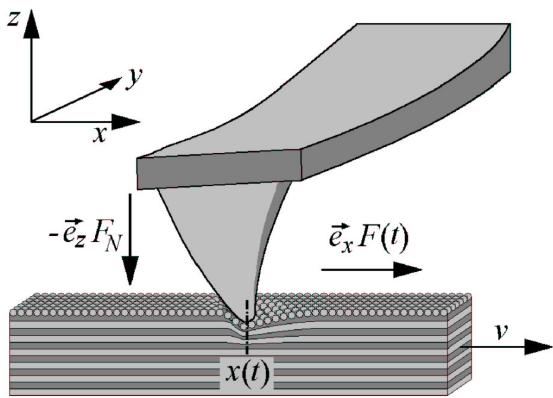
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$\Rightarrow$ goal: equation of motion for $x(t)$

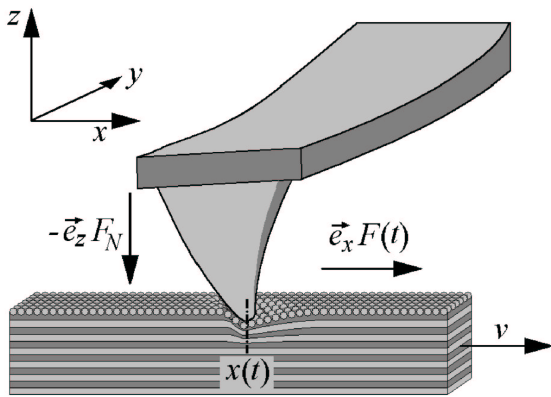


$x = x(t)$: position of tip apex (rest position $x = 0$)

$s = vt$: position of substrate along x -axis

substrate potential $U(x-s)$ with $U(x+L) = U(x)$

elastic force $-\kappa x(t) = -F(t)$ [$\kappa \approx 1$ nN/nm]



$x = x(t)$: position of tip apex (rest position $x = 0$)

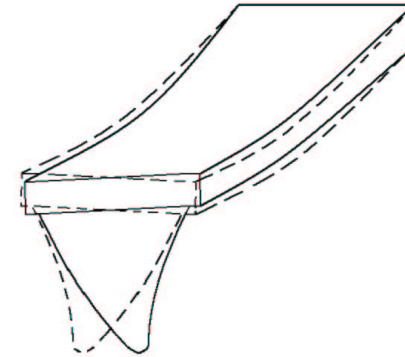
$s = vt$: position of substrate along x -axis

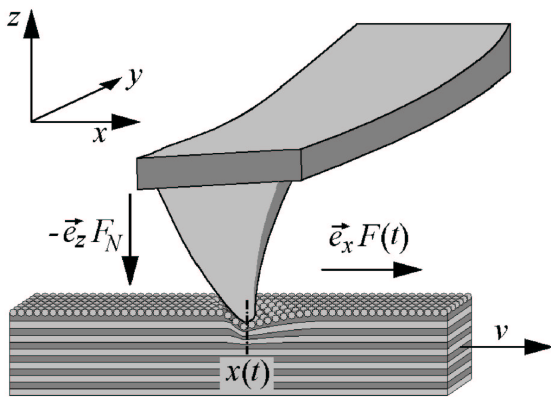
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“fast” fluctuations of molecules $\Rightarrow$ thermal bath effects (close to eq.)

- dissipation of cantilever & tip $-\eta_c \dot{x}(t)$
- concomitant thermal noise $\sqrt{2\eta_c kT} \xi_c(t)$





$x = x(t)$: position of tip apex (rest position $x = 0$)

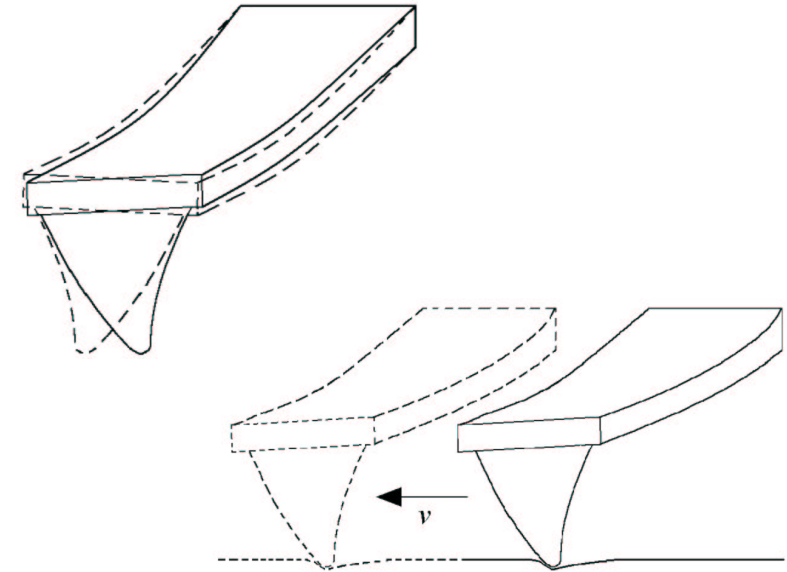
$s = vt$: position of substrate along x -axis

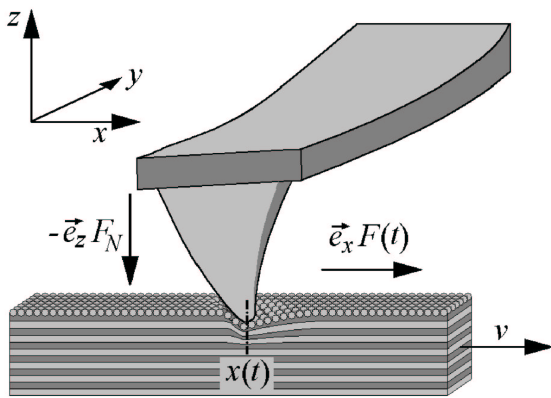
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- concomitant thermal noise $\sqrt{2\eta_s kT} \xi_s(t)$





$x = x(t)$: position of tip apex (rest position $x = 0$)

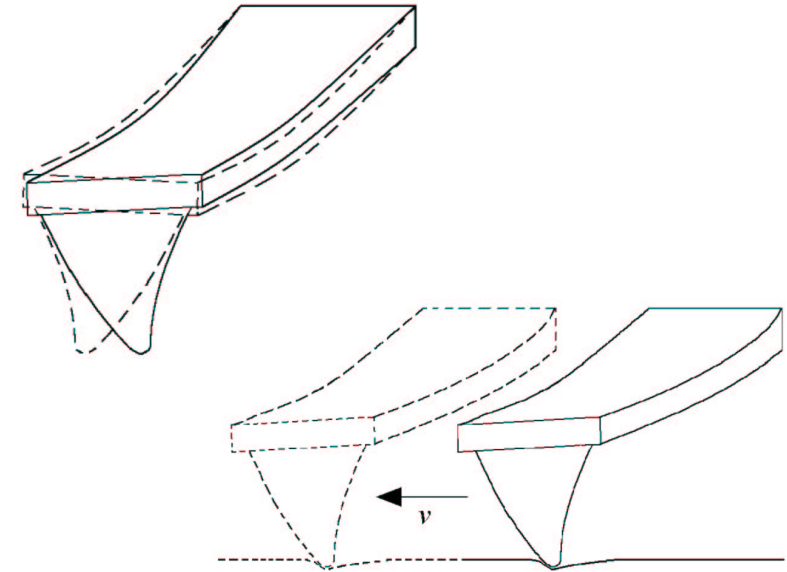
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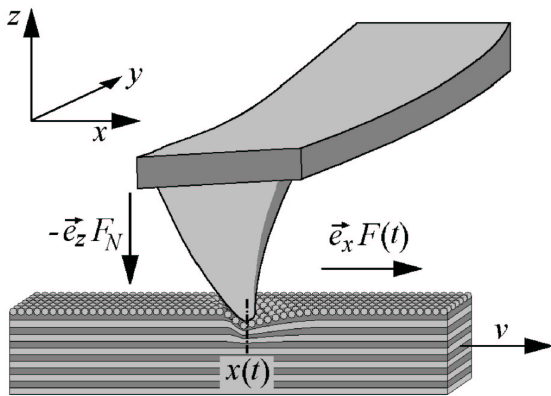
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$$m\ddot{x}(t) = -U'(x(t)-vt) - \kappa x(t) - \eta_c \dot{x}(t) + \sqrt{2\eta_c kT} \xi_c(t) - \eta_s (\dot{x}(t) - v) + \sqrt{2\eta_s kT} \xi_s(t)$$



$x = x(t)$: position of tip apex (rest position $x = 0$)

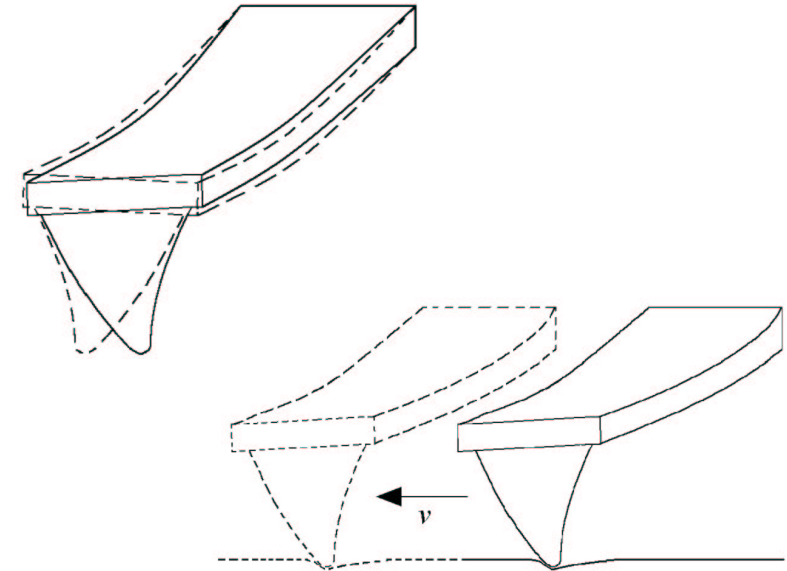
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$$\eta := \eta_c + \eta_s, \quad \vartheta := \eta_c / \eta, \quad X(t) := x(t) - vt, \quad F(t) = \kappa x(t) = \kappa (X(t) + vt)$$

$$m \ddot{X}(t) = -U'(X(t)) - F(t) - \vartheta \eta v - \eta \dot{X}(t) + \sqrt{2\eta kT} \xi(t)$$